

<b>Notice of References Cited</b>	Application/Control No. 10/790,747	Applicant(s)/Patent Under Reexamination LAUFFER ET AL.	
	Examiner Hoa C. Nguyen	Art Unit 2841	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,040,524	03-2000	Kobayashi et al.	174/36
*	B	US-6,353,189	03-2002	Shimada et al.	174/255
*	C	US-6,010,769	01-2000	Sasaoka et al.	428/209
*	D	US-6,236,572	05-2001	Teshome et al.	361/794
*	E	US-5,455,393	10-1995	Ohshima et al.	174/250
*	F	US-5,662,816	09-1997	Andry, Steven C.	216/18
*	G	US-6,657,130	12-2003	Van Dyke et al.	174/255
*	H	US-6,239,485	05-2001	Peters et al.	257/700
*	I	US-6,992,255	01-2006	Oprysko et al.	174/262
*	J	US-2004/0009666	01-2004	Ishizuki et al.	438/689
*	K	US-6,239,485	05-2001	Peters et al.	257/700
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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	X	

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